K Vedam

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#	Paper	IF	Citations
157	Dielectric and Thermal Study of (NH4)2SO4 and (NH4)2BeF4 Transitions. <i>Physical Review</i> , 1958 , 112, 405-412		181
156	Nondestructive depth profiling by spectroscopic ellipsometry. <i>Applied Physics Letters</i> , 1985 , 47, 339-34	413.4	116
155	Spectroscopic ellipsometry: a historical overview. <i>Thin Solid Films</i> , 1998 , 313-314, 1-9	2.2	114
154	Ammonium Hydrogen Sulfate: A New Ferroelectric with Low Coercive Field. <i>Physical Review</i> , 1958 , 111, 1508-1510		112
153	Thin-film deposition by a new laser ablation and plasma hybrid technique. <i>Applied Physics Letters</i> , 1989 , 54, 2455-2457	3.4	111
152	Spectroscopic ellipsometry: A new tool for nondestructive depth profiling and characterization of interfaces. <i>Journal of Applied Physics</i> , 1986 , 59, 694-701	2.5	104
151	Investigation of the void structure in amorphous germanium thin films as a function of low-energy ion bombardment. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1988 , 6, 1631-1635	2.9	86
150	Optical Anisotropy of Silicon Single Crystals. <i>Physical Review B</i> , 1971 , 3, 2567-2571	3.3	83
149	LiH3(SeO3)2: New Room-Temperature Ferroelectric. <i>Physical Review</i> , 1959 , 114, 1217-1218		83
148	Ferroelectricity in Di-Glycine Nitrate (NH2CH2COOH)2[HNO3. <i>Physical Review</i> , 1958 , 111, 430-432		82
147	Variation of Refractive Index of MgO with Pressure to 7 kbar. <i>Physical Review</i> , 1966 , 146, 548-554		82
146	Ferroelectric Transition in Rubidium Bisulfate. <i>Physical Review</i> , 1960 , 117, 1502-1503		81
145	Room-Temperature Ferroelectricity in Lithium Hydrazinium Sulfate, Li (N2H5)SO4. <i>Physical Review</i> , 1958 , 111, 1467-1468		77
144	Direct Optical Observation of the Semiconductor-to-Metal Transition in SmS under Pressure. <i>Physical Review B</i> , 1972 , 6, 3023-3026	3.3	74
143	Fast scanning spectroelectrochemical ellipsometry: In-situ characterization of gold oxide. <i>Surface Science</i> , 1990 , 233, 341-350	1.8	66
142	Piezo- and elasto-optic properties of liquids under high pressure. II. Refractive index vs density. Journal of Chemical Physics, 1978 , 69, 4772-4778	3.9	63
141	Piezo- and elasto-optic properties of liquids under high pressure. I. Refractive index vs pressure and strain. <i>Journal of Chemical Physics</i> , 1978 , 69, 4762-4771	3.9	63

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140	Variation of the refractive indices of CaF2, BaF2 and IPbF2 with pressure to 7 kb. <i>Journal of Physics and Chemistry of Solids</i> , 1966 , 27, 1563-1566	3.9	62
139	Real Time Spectroscopic Ellipsometry: In Situ Characterization of Pyrrole Electropolymerization. <i>Journal of the Electrochemical Society</i> , 1991 , 138, 3266-3275	3.9	55
138	Characterization of real surfaces by ellipsometry. <i>Surface Science</i> , 1972 , 29, 379-395	1.8	51
137	Ellipsometric Method for the Determination of All the Optical Parameters of the System of an Isotropic Nonabsorbing Film on an Isotropic Absorbing Substrate Optical Constants of Silicon*. <i>Journal of the Optical Society of America</i> , 1969 , 59, 64		50
136	Elastic Constants of Selenium in the Hexagonal and Glassy Phases. <i>Journal of Applied Physics</i> , 1966 , 37, 3432-3434	2.5	50
135	Pressure Dependence of the Refractive Indices of the Hexagonal Crystals Beryl,ECdS,EZnS, and ZnO. <i>Physical Review</i> , 1969 , 181, 1196-1201		49
134	Raman spectrum of strontium titanate. European Physical Journal A, 1961, 163, 158-164	2.5	47
133	Nonlinear Variation of Refractive Index of Vitreous Silica with Pressure to 7 Kbars. <i>Journal of the American Ceramic Society</i> , 1966 , 49, 531-535	3.8	46
132	New Room-Temperature Ferroelectric. <i>Physical Review</i> , 1958 , 110, 1309-1311		45
131	Pressure Dependence of the Refractive Indices of the Tetragonal Crystals: ADP, KDP, CaMoO_4, CaWO_4, and Rutile*. <i>Journal of the Optical Society of America</i> , 1968 , 58, 1446		44
130	Generalized Ellipsometric Method for the Absorbing Substrate Covered with a Transparent-Film		42
	System Optical Constants of Silicon at 3655 \alpha. Journal of the Optical Society of America, 1972 , 62, 16		
129	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire and Pt-coated silicon substrates. <i>Thin Solid Films</i> , 1993 , 230, 15-27	2.2	41
129	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire	2.2	41 40
	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire and Pt-coated silicon substrates. <i>Thin Solid Films</i> , 1993 , 230, 15-27 Nonlinear Variation of the Refractive Indices of EQuartz with Pressure*. <i>Journal of the Optical</i>	2.2	
128	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire and Pt-coated silicon substrates. <i>Thin Solid Films</i> , 1993 , 230, 15-27 Nonlinear Variation of the Refractive Indices of EQuartz with Pressure*. <i>Journal of the Optical Society of America</i> , 1967 , 57, 1140 Effect of preparation conditions on the morphology and electrochromic properties of amorphous tungsten oxide films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1993		40
128	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire and Pt-coated silicon substrates. <i>Thin Solid Films</i> , 1993 , 230, 15-27 Nonlinear Variation of the Refractive Indices of EQuartz with Pressure*. <i>Journal of the Optical Society of America</i> , 1967 , 57, 1140 Effect of preparation conditions on the morphology and electrochromic properties of amorphous tungsten oxide films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1993 , 11, 1881-1887 Optical characterization of a four-medium thin film structure by real time spectroscopic	2.9	40
128 127 126	Spectroscopic ellipsometry studies on ion beam sputter deposited Pb(Zr, Ti)O3 films on sapphire and Pt-coated silicon substrates. <i>Thin Solid Films</i> , 1993 , 230, 15-27 Nonlinear Variation of the Refractive Indices of EQuartz with Pressure*. <i>Journal of the Optical Society of America</i> , 1967 , 57, 1140 Effect of preparation conditions on the morphology and electrochromic properties of amorphous tungsten oxide films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1993 , 11, 1881-1887 Optical characterization of a four-medium thin film structure by real time spectroscopic ellipsometry: amorphous carbon on tantalum. <i>Applied Optics</i> , 1991 , 30, 2692-703 Thickness dependence of optical gap and void fraction for sputtered amorphous germanium.	2.9 1.7	40 39 39

122	Simultaneous determination of dispersion relation and depth profile of thorium fluoride thin film by spectroscopic ellipsometry. <i>Thin Solid Films</i> , 1988 , 166, 325-334	2.2	37
121	Roughness measurements by spectroscopic ellipsometry. <i>Applied Optics</i> , 1985 , 24, 3773	1.7	37
120	Analytic solution of the pseudo-Brewster angle. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 1986 , 3, 1772	1.8	37
119	Non-isomorphism of ferroelectric phases of ammonium sulfate and ammonium fluoberyllate. <i>Acta Crystallographica</i> , 1958 , 11, 307-307		37
118	Proper choice of the error function in modeling spectroellipsometric data. <i>Applied Optics</i> , 1986 , 25, 20	13 _{1.7}	35
117	Formation and nondestructive characterization of ion implanted silicon-on-insulator layers. <i>Applied Physics Letters</i> , 1987 , 51, 343-345	3.4	34
116	Density of amorphous germanium films by spectroscopic ellipsometry. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1986 , 4, 577-582	2.9	33
115	Ion-implantation induced anomalous surface amorphization in silicon. <i>Nuclear Instruments & Methods in Physics Research B</i> , 1994 , 85, 335-339	1.2	32
114	Real-time and spectroscopic ellipsometry characterizatio of diamond and diamond-like carbon. <i>Thin Solid Films</i> , 1989 , 181, 565-578	2.2	30
113	Variation of the refractive indices of KBr and KI with pressure to 14 kbars. <i>Materials Research Bulletin</i> , 1969 , 4, 573-579	5.1	30
112	The Laser as a Light Source for Ultramicroscopy and Light Scattering by Imperfections in Crystals. Investigation of Imperfections in LiF, MgO, and Ruby. <i>Journal of Applied Physics</i> , 1966 , 37, 2551-2557	2.5	30
111	Simultaneous determination of refractive index, its dispersion and depth-profile of magnesium oxide thin film by spectroscopic ellipsometry. <i>Applied Optics</i> , 1989 , 28, 2691-4	1.7	27
110	Spectroscopic ellipsometry studies of crystalline silicon implanted with carbon ions. <i>Journal of Applied Physics</i> , 1990 , 67, 3555-3559	2.5	27
109	Simultaneous and Independent Determination of the Refractive Index and the Thickness of Thin Films by Ellipsometry*. <i>Journal of the Optical Society of America</i> , 1968 , 58, 526		27
108	Real time spectroscopic ellipsometry characterization of the nucleation of diamond by filament-assisted chemical vapor deposition. <i>Journal of Applied Physics</i> , 1992 , 71, 5287-5289	2.5	26
107	Determination of the optical constants of an inhomogeneous transparent LaF(3) thin film on a transparent substrate by spectroscopic ellipsometry. <i>Optics Letters</i> , 1992 , 17, 538-40	3	26
106	Thickness-dependent void fraction of rf-sputtered amorphous Ge films by spectroscopic ellipsometry. <i>Applied Physics Letters</i> , 1986 , 49, 328-330	3.4	25
105	Determination of the optical function n() of vitreous silica by spectroscopic ellipsometry with an achromatic compensator. <i>Applied Optics</i> , 1993 , 32, 6391-8	1.7	24

104	Generalized ellipsometric method for the determination of all the optical constants of the system: Optically absorbing film on an absorbing substrate. <i>Surface Science</i> , 1976 , 56, 49-63	1.8	24	
103	Photoelastic Properties of Sapphire (FAl2O3). Journal of Applied Physics, 1967, 38, 4555-4556	2.5	24	
102	Nondestructive depth profiling of ZnS and MgO films by spectroscopic ellipsometry. <i>Optics Letters</i> , 1987 , 12, 456-8	3	23	
101	Piezo- and elasto-optic properties of liquids under high pressure. III. Results on twelve more liquids. Journal of Chemical Physics, 1980 , 73, 4577-4584	3.9	23	
100	Characterization of inhomogeneous transparent thin films on transparent substrates by spectroscopic ellipsometry: refractive indices n() of some fluoride coating materials. <i>Applied Optics</i> , 1994 , 33, 2664-71	1.7	22	
99	Explosive crystallization of rf-sputtered amorphous CdTe films. <i>Journal of Electronic Materials</i> , 1981 , 10, 433-443	1.9	22	
98	Characterization of defects in real surfaces by ellipsometry. Surface Science, 1976 , 56, 221-236	1.8	22	
97	The Elastic and Photoelastic Constants of Fused Quartz. <i>Physical Review</i> , 1950 , 78, 472-473		22	
96	Characterization of ion beam-induced surface modification of diamond films by real time spectroscopic ellipsometry. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1991 , 9, 1123-1128	2.9	21	
95	Pressure dependence of the refractive index and dielectric constant in a fluoroperovskite, KMgF3. <i>Physical Review B</i> , 1984 , 29, 6921-6925	3.3	20	
94	Characterization of real surfaces of vitreous silica by ellipsometry. <i>Materials Research Bulletin</i> , 1974 , 9, 1503-1509	5.1	20	
93	Refractive index of liquids at high pressures. <i>Critical Reviews in Solid State and Materials Sciences</i> , 1983 , 11, 1-45	10.1	19	
92	Ar ion beam and CCl4 reactive ion etching: A comparison of etching damage and of damage passivation by hydrogen. <i>Journal of Applied Physics</i> , 1985 , 58, 4282-4291	2.5	19	
91	Spectroscopic ellipsometry study of glow-discharge-deposited thin films of a-Ge:H. <i>Journal of Applied Physics</i> , 1986 , 60, 3724-3731	2.5	19	
90	Optical interferometry in liquids at high pressures to 14 kilobars. <i>Review of Scientific Instruments</i> , 1977 , 48, 245-246	1.7	19	
89	Epitaxial Growth of Ice Crystals on the Muscovite Cleavage Plane and Their Relation to Partial Dislocations. <i>Journal of Applied Physics</i> , 1971 , 42, 516-520	2.5	19	
88	Electrical characteristics of r.fsputtered CdTe thin-films for photovoltaic applications. <i>Solid-State Electronics</i> , 1984 , 27, 329-337	1.7	18	
87	Piezo-optic Behavior of Water and Carbon Tetrachloride under High Pressure. <i>Physical Review Letters</i> , 1975 , 35, 1014-1016	7.4	18	

86	Characterization of the interface between Ge+-implanted crystalline silicon and its thermally grown oxide by spectroscopic ellipsometry. <i>Journal of Applied Physics</i> , 1990 , 67, 599-603	2.5	17
85	Retroreflection from spherical glass beads in highway pavement markings. 1: Specular reflection. <i>Applied Optics</i> , 1978 , 17, 1855-8	1.7	17
84	Non-linear piezo-optics. Acta Crystallographica, 1967 , 22, 630-634		17
83	Monitoring ion etching of GaAs/AlGaAs heterostructures by real time spectroscopic ellipsometry: Determination of layer thicknesses, compositions, and surface temperature. <i>Applied Physics Letters</i> , 1992 , 60, 2776-2778	3.4	16
82	Studies on inhomogeneous transparent optical coatings on transparent substrates by spectroscopic ellipsometry. <i>Thin Solid Films</i> , 1993 , 234, 439-442	2.2	16
81	Speckle photography of lateral sinusoidal vibrations: error due to varying halo intensity. <i>Applied Optics</i> , 1981 , 20, 3388-91	1.7	16
80	Importance of using Eulerian representation of strain in high pressure studies on liquids. <i>Journal of Chemical Physics</i> , 1982 , 77, 1461-1463	3.9	16
79	Piezo- and thermo-optic behavior of spinel (MgAl2O4). Journal of Solid State Chemistry, 1975, 12, 213-	21 § .3	16
78	Retroreflection from spherical glass beads in highway pavement markings. 2: Diffuse reflection (a first approximation calculation). <i>Applied Optics</i> , 1978 , 17, 1859-69	1.7	16
77	Optical Characterization of Inhomogeneous Transparent Films on Transparent Substrates by Spectroscopic Ellipsometry. <i>Physics of Thin Films</i> , 1994 , 191-247		15
76	Processing speckle photography data: circular imaging aperture. <i>Applied Optics</i> , 1983 , 22, 653-4	1.7	15
75	Piezo-Optic Properties of Amorphous Selenium at a Wavelength of 115 [] <i>Journal of the Optical Society of America</i> , 1970 , 60, 800		15
74	Nonlinear Piezo-Optic Behavior of Sphalerite (EZnS). <i>Physical Review</i> , 1966 , 150, 766-767		15
73	Ion beam etching of GaAs and GaAs/AlGaAs heterostructures probed in real time by spectroscopic ellipsometry. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1991 , 9, 810-81	5 ^{2.9}	14
72	High-dose carbon ion implantation studies in silicon. <i>Thin Solid Films</i> , 1988 , 163, 323-329	2.2	13
71	Finite size effects on lattice vibrations of ionic crystals and measurements of infrared absorption spectra. <i>Physica Status Solidi A</i> , 1970 , 3, 647-656		13
70	Piezo-optic behavior of forsterite, Mg2SiO4. Journal of Physics and Chemistry of Solids, 1972, 33, 1251-	1255	13
69	Piezo-optic behaviour of rubidium chloride up to the phase transition point. <i>Journal of Materials Science</i> , 1966 , 1, 310-312	4.3	13

68	Elastic and photoelastic properties of some optical glasses. <i>Proceedings of the Indian Academy of Sciences - Section A</i> , 1950 , 31, 450-458		13	
67	Real-time spectroscopic ellipsometry study of theelectrochemical deposition of polypyrrole thin films. <i>Thin Solid Films</i> , 1990 , 193-194, 350-360	2.2	12	
66	Selective counting path of Young fringes in speckle photography for eliminating diffraction halo effects. <i>Applied Optics</i> , 1983 , 22, 2242-3	1.7	12	
65	Ellipsometric studies of environment-sensitive polish layers of glass. <i>Journal of Applied Physics</i> , 1977 , 48, 1155-1157	2.5	12	
64	Examination of Imperfect Muscovite Crystals by X-Ray Diffraction Methods. <i>Journal of Applied Physics</i> , 1970 , 41, 50-53	2.5	12	
63	PIEZO- AND THERMO-OPTIC BEHAVIOR OF LINBO3. <i>Applied Physics Letters</i> , 1968 , 12, 138-140	3.4	11	
62	Variation of the refractive index of boric oxide glasses with hydrostatic pressure to 7 kbar. <i>Journal of Applied Physics</i> , 1972 , 43, 3623-3627	2.5	11	
61	Nondestructive Depth-Profiling of Multilayer Structures by Spectroscopic Ellipsometry. <i>MRS Bulletin</i> , 1987 , 12, 21-23	3.2	10	
60	Real time monitoring of filament-assisted chemically vapor deposited diamond by spectroscopic ellipsometry. <i>Surface and Coatings Technology</i> , 1991 , 49, 381-386	4.4	9	
59	Ion-implantation-caused special damage profiles determined by spectroscopic ellipsometry in crystalline and in relaxed (annealed) amorphous silicon. <i>Thin Solid Films</i> , 1993 , 233, 117-121	2.2	9	
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57	Optical Constants of Silicon at 5461 🖁. <i>Journal of the Optical Society of America</i> , 1972 , 62, 596		9	
56	Comparative study of the effect of annealing of nitrogen-implanted silicon-on-insulator structures by spectroscopic ellipsometry, cross-sectional transmission electron microscopy and Rutherford backscattering spectroscopy. <i>Materials Science and Engineering B: Solid-State Materials for Advanced</i>	3.1	8	
55	Technology, 1992, 12, 177-184 Hydrogen diffusion and reaction processes in thin films investigated by real time spectroscopic ellipsometry. <i>Thin Solid Films</i> , 1993, 233, 276-280	2.2	8	
54	Intrinsic Stress in a-Germanium Films Deposited by RF-Magnetron Sputtering. <i>Materials Research Society Symposia Proceedings</i> , 1988 , 130, 355		8	
53	Measurement of subspeckle-size changes by laser-speckle photography. <i>Optics Letters</i> , 1979 , 4, 406	3	8	
52	The study of dislocations in muscovite mica by X-ray transmission topography. <i>Philosophical Magazine and Journal</i> , 1970 , 22, 255-268		8	
51	Nonuniformity in void concentration between the initial and final growth stage of sputtered a-Ge films studied using spectroscopic ellipsometry. <i>Physical Review B</i> , 1987 , 36, 6206-6208	3.3	7	

50	Spectroscopic Ellipsometry Study of rf-Sputtered a-Ge Films. <i>Materials Research Society Symposia Proceedings</i> , 1984 , 38, 301		7
49	A critical evaluation of equations of state by piezo-optic measurements. <i>Journal of Applied Physics</i> , 1979 , 50, 1328-1333	2.5	7
48	THIN FILM CHARACTERIZATION BY ELECTRON MICROPROBE AND ELLIPSOMETRY: SiO2 FILMS ON SILICON. <i>Applied Physics Letters</i> , 1969 , 14, 43-45	3.4	7
47	Characterisation of thin surface films on germanium in various solvents by ellipsometry. <i>Journal of Materials Science</i> , 1971 , 6, 969-973	4.3	7
46	Variation of the refractive indices of calcite, with pressure to 7 kbar. <i>Physica Status Solidi (B): Basic Research</i> , 1968 , 26, 285-290	1.3	7
45	Photoelastic properties of barite. <i>Proceedings of the Indian Academy of Sciences - Section A</i> , 1951 , 34, 161		7
44	Photoelastic constants of sodium chlorate from ultrasonic diffraction. <i>Proceedings of the Indian Academy of Sciences - Section A</i> , 1951 , 34, 240		6
43	Real-time spectroscopic ellipsometry for determination of the optical functions of ion-beam-deposited hydrogenated amorphous carbon. <i>Thin Solid Films</i> , 1990 , 193-194, 361-370	2.2	5
42	Direct observation of laser speckles for real-time analysis of lateral motions. <i>Optics Letters</i> , 1981 , 6, 51	1-3	5
41	Optical constants of germanium by ellipsometry. <i>Physics Letters, Section A: General, Atomic and Solid State Physics</i> , 1969 , 29, 428-429	2.3	5
40	Nonlinear variation of the induced birefringence of vitreous silica with uniaxial stress to 7 kbar. <i>Journal of Applied Physics</i> , 1972 , 43, 3724-3728	2.5	5
39	Dispersion of the Elasto-Optic Constants of Potassium Halides 1975 , 169-177		5
38	Morphology Control Of The Electrochromic Effect In Tungsten Oxide Thin Films. <i>Materials Research Society Symposia Proceedings</i> , 1991 , 255, 275		4
37	Electrical, Optical and Structural Properties of Thin SiO2 Films On Si. <i>Materials Research Society Symposia Proceedings</i> , 1987 , 105, 169		4
36	Spectroscopic ellipsometry of amorphous Ni0.95Tb0.05 and crystalline nickel. <i>Materials Science and Engineering</i> , 1988 , 99, 281-283		4
35	Complete 3-D deformation analysis in the white light speckle method. <i>Applied Optics</i> , 1983 , 22, 213-4	1.7	4
34	Stress-optic coefficient of ZnSe at 10.6 microm. <i>Applied Optics</i> , 1981 , 20, 2878-9	1.7	4
33	Variation of refractive index of polystyrene with pressure to 7 kbar. <i>Journal of Applied Physics</i> , 1976 , 47, 2443-2446	2.5	4

32	Hardening of CaF2 single-crystal surfaces due to contamination by atmospheric oxygen. <i>Journal of Applied Physics</i> , 1972 , 43, 4396-4400	2.5	4
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30	Spectroscopic ellipsometry of sputtered amorphous Ni0.95Tb. <i>Physical Review B</i> , 1988 , 38, 1562-1565	3.3	3
29	Characterization of Ion Implanted Silicon by Spectroscopic Ellipsometry and Cross Section Transmission Electron Microscopy. <i>Materials Research Society Symposia Proceedings</i> , 1983 , 27, 299		3
28	Characterization of surfaces of laser-annealed samples by ellipsometry. Surface Science, 1980 , 96, 319-3	2:8 8	3
27	Laser speckle photography for supersensitive dial gauge. <i>Optics Letters</i> , 1980 , 5, 441-2	3	3
26	The Study of Damage Profile of Ion Implanted Layer on Si by Spectroscopic Ellipsometry. <i>Materials Research Society Symposia Proceedings</i> , 1982 , 14, 529		3
25	Growth of color centres and hardening of CaF2 by heavy dose of 且rradiation. <i>Physica Status Solidi A</i> , 1973 , 19, 625-634		3
24	Application of fringe shifting technique in speckle photography 1979 , 12, 341-346		2
23	Unusual white light conoscopic figure in single crystal lithium metagermanate Li(2)GeO(3). <i>Applied Optics</i> , 1978 , 17, 3339_1	1.7	2
22	OPTICAL STUDIES ON THE HIGH PRESSURE PHASE TRANSFORMATIONS IN SILVER IODIDE SINGLE CRYSTALS 1973 , 91-99		2
21	High Dose Carbon Ion Implantation Studies in Silicon. <i>Materials Research Society Symposia Proceedings</i> , 1987 , 107, 483		1
20	Processing & Characterization Of Thin Films Of SiO 2 On Si For Integrated Circuits 1988 , 0945, 84		1
19	Surface Roughness Characterization of Al Films by Spectroscopic Ellipsometry. <i>Materials Research Society Symposia Proceedings</i> , 1985 , 54, 669		1
18	Supersensitive Dial-Gage Measurement by Observing Rotation of Laser Speckles. <i>Experimental Techniques</i> , 1985 , 9, 16-17	1.4	1
17	Testing the trueness of circular surfaces: a simple holographic method. <i>Applied Optics</i> , 1979 , 18, 627-30	1.7	1
16	Testing the trueness of circular surfaces by laser speckle photography. <i>Applied Optics</i> , 1979 , 18, 2351-3	1.7	1
15	Piezo- and elasto-optic properties of deuterium oxide under high pressure. <i>Journal of Chemical Physics</i> , 1980 , 72, 1410-1411	3.9	1

Characterization of Ferroelectric Films by Spectroscopic Ellipsometry. Physics of Thin Films, 1994, 249-278 14 7 5.2.2.5 Trigonal system: Classes 3m (C(3v)), 32 (D(3)), (-3)m (D(3d))59-62 13 Formation And Nondestructive Characterization Of Ion Implanted Soi Layers 1987, 0797, 77 12 SIMULTANEOUS DETERMINATION OF DISPERSION RELATION AND DEPTH PROFILE OF THORIUM 11 FLUORIDE THIN FILM BY SPECTROSCOPIC ELLIPSOMETRY 1988, 325-334 5.2.1 Comments on tabulated data17-18 10 Magnesium - Potassium 32-38 9 8 Rubidium - Zirconium39-49 5.2.2.3 Hexagonal system: Classes (-6)m2 (D{3h}), 6mm (C{6v}), 622 (D{6}), 6/mm (D{6h})56-57 5.2.2.9 Orthorhombic system: All classes, 222 (D{2}), mm2 (C{2v}), mmm (D{2h})71-81 6 Figs. 48 - 99101-113 Figs. 151 - 196127-139 Real time monitoring of filament-assisted chemically vapor deposited diamond by spectroscopic ellipsometry **1991**, 381-386 The Pressure Dependence of the Magnetic Susceptibility of Rare-Earth Substituted Samarium Sulfide 1978, 187-204 Piezo-Optic Behavior and the Equation of State of Liquids 1979, 421-427